(12) INTERNATIONAL APPLICATION PUBLISHED UNDER THE PATENT COOPERATION TREATY (PCT)

(19) World Intellectual Property Organization

International Bureau





(43) International Publication Date 13 October 2005 (13.10.2005)

PCT

(10) International Publication Number WO 2005/096355 A1

- (51) International Patent Classification⁷: H01L 21/20, 21/205, 21/338, 29/26, 29/778, 29/812, 29/861, 33/00
- (21) International Application Number:

PCT/JP2005/006534

- (22) International Filing Date: 28 March 2005 (28.03.2005)
- (25) Filing Language: English
- (26) Publication Language: English
- (30) Priority Data: 2004-098876 30 March 2004 (30.03.2004) JP 60/560.268 8 April 2004 (08.04.2004) US
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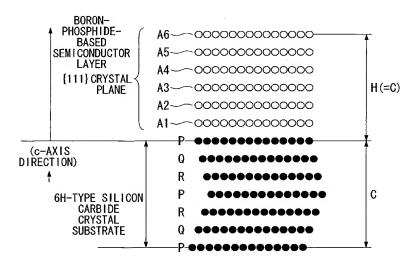
- (81) Designated States (unless otherwise indicated, for every kind of national protection available): AE, AG, AL, AM, AT, AU, AZ, BA, BB, BG, BR, BW, BY, BZ, CA, CH, CN, CO, CR, CU, CZ, DE, DK, DM, DZ, EC, EE, EG, ES, FI, GB, GD, GE, GH, GM, HR, HU, ID, IL, IN, IS, KE, KG, KP, KR, KZ, LC, LK, LR, LS, LT, LU, LV, MA, MD, MG, MK, MN, MW, MX, MZ, NA, NI, NO, NZ, OM, PG, PH, PL, PT, RO, RU, SC, SD, SE, SG, SK, SL, SM, SY, TJ, TM, TN, TR, TT, TZ, UA, UG, US, UZ, VC, VN, YU, ZA, ZM, ZW.
- (84) Designated States (unless otherwise indicated, for every kind of regional protection available): ARIPO (BW, GH, GM, KE, LS, MW, MZ, NA, SD, SL, SZ, TZ, UG, ZM, ZW), Eurasian (AM, AZ, BY, KG, KZ, MD, RU, TJ, TM), European (AT, BE, BG, CH, CY, CZ, DE, DK, EE, ES, FI, FR, GB, GR, HU, IE, IS, IT, LT, LU, MC, NL, PL, PT, RO, SE, SI, SK, TR), OAPI (BF, BJ, CF, CG, CI, CM, GA, GN, GQ, GW, ML, MR, NE, SN, TD, TG).

Published:

with international search report

[Continued on next page]

(54) Title: COMPOUND SEMICONDUCTOR DEVICE, PRODUCTION METHOD OF COMPOUND SEMICONDUCTOR DEVICE AND DIODE



(57) Abstract: A compound semiconductor device includes hexagonal silicon carbide crystal substrate and a boron-phosphide-based semiconductor layer formed on the silicon carbide crystal substrate, wherein the silicon carbide crystal substrate has a surface assuming a (0001) crystal plane, and the boron-phosphide-based semiconductor layer is composed of a 11111 crystal stacked on and in parallel with the {0001} crystal plane of the silicon carbide crystal substrate, and when the number of the layers contained in one periodical unit of an atomic arrangement in the [0001] crystal orientation of the silicon carbide crystal substrate is n, an n-layer-stacked structure included in the { 111 } crystal plane forming the { 111 } crystal has a stacking height virtually equal to the c-axis lattice constant of the silicon carbide crystal substrate.



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